Receipt

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

fre the Application of: Hiroyuki SHINOZAKI

Spial Number: 09/875,134

Filed: June 7, 2001

Group Art Unit: 3652

Attention: Appln Processing Division,

Customer Correction Branch

For: SUBSTRATE ROTATING APPARATUS

REQUEST FOR CORRECTED FILING RECEIPT

Commissioner for Patents Washington, D.C. 20231

Date: August 23, 20

Sir:

Please supply the undersigned attorney with a corrected filing receipt for the above identified application. The undersigned also respectfully requests that the Patent and Trademark Office records be amended to reflect the correction.

In reviewing the official Filing Receipt, we have noted an error in that the foreign filing date of the priority document is incorrect ("09/06/2000" should be - -06/09/2000- -). A copy of the Declaration is enclosed which indicates the correct date.

We are enclosing a copy of the filing receipt with the corrections highlighted.

In the event that any fees are required in connection with this paper, please charge our Deposit Account No. 01-2340. RECEIVED

Respectfully submitted,

AUG 31

ARMSTRONG, WESTERMAN, HATTORI, McLELAND & NAUGHTON, LLP

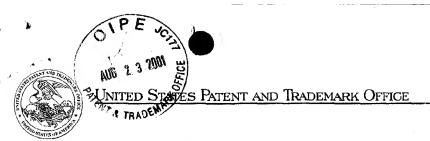
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Enclosures: Copies of Filing Receipt & Declaration



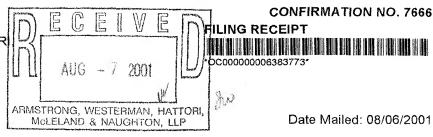
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 APPLICATION NUMBER
 FILING DATE
 GRP ART UNIT
 FIL FEE REC'D
 ATTY.DOCKET.NO
 DRAWINGS
 TOT CLAIMS
 IND CLAIMS

 09/875,134
 06/07/2001
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23850 ARMSTRONG,WESTERMAN, HATTOR MCLELAND & NAUGHTON, LLP 1725 K STREET, NW, SUITE 1000 WASHINGTON, DC 20006



Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Hiroyuki Shinozaki, Kanagawa-ken, JAPAN;

Assignment For Published Patent Application

Ebara Corporation, Tokyo, JAPAN;

Domestic Priority data as claimed by applicant

Foreign Applications

cations 06/09/2000 JAPAN 2000/173689 09/06/2000

If Required, Foreign Filing License Granted 08/03/2001

Projected Publication Date: 03/07/2002

Non-Publication Request: No

Early Publication Request: No

Title

Substrate rotating apparatus

Preliminary Class

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AUG 31 2001

